



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

KABASAWA

Art Unit: 2881

Application Number: 09/629,618

Examiner: B. Souw

Filed: July 31, 2000

Atty. Docket No.: 107443-00007

For: ION IMPLANTATION APPARATUS AND ION IMPLANTATION METHOD

AMENDMENT UNDER 37 C.F.R. § 1.116

Commissioner for Patents
Washington, D.C. 20231

Date: April 9, 2003

Sir:

This paper is filed in response to the Office Action dated December 9, 2002, in connection with the above-identified patent application. Applicants respectfully request entry of the following amendments.

IN THE CLAIMS.

Please amend claims 4, 6, 9, 22 and 23 as follows. Attached is a marked-up copy showing changes to the claims.

4. (Thrice Amended) The ion implantation apparatus as claimed in claim 3, further comprising means for measuring the correlation from an inverse proportion relation between the energy contamination and the beam transport efficiency.

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